

500.41316VX1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. KAJI, et al

Serial No.: 10/090,759

Filed: September 11, 2003

For: EMISSION SPECTROSCOPIC PROCESSING APPARATUS
AND PLASMA PROCESSING METHOD USING IT

REAFFIRMATION OF CLAIM FOR PRIORITY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 11, 2003

Sir:

Under the provisions of 35 USC §119 and 37 CFR §1.55, Applicants hereby claim the right of priority based on Japanese Patent Application No. 2001-364626, filed in Japan on November 29, 2001.

The certified copy of the above-referred to Japanese Patent Application was filed on April 29, 2002 in prior application Serial No. 10/090,759, filed March 6, 2002.

Respectfully submitted,



Melvin Kraus
Registration No. 22,466
ANTONELLI, TERRY, STOUT & KRAUS, LLP

MK/cee
(703) 312-6600